~~What is claimed is~~:
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1. A micromechanical yaw rate sensor, comprising;
a substrate (100) having an anchoring device (21; 21') provided on the substrate (100); and having an annular flywheel (10) that is connected via a flexural spring device (30, 31; 32, 33) with the anchoring device (21; 21'; 25') in such a way that the area of connection with the anchoring device (21; 21'; 25') is located essentially in the center of the ring, so that the annular flywheel (10) is able to be displaced, elastically from its rest position, about an axis of rotation situated perpendicular to the substrate surface, and about at least one axis of rotation situated parallel to the substrate surface;
wherein the anchoring device (21; 21'; 25') has two opposite bases (21; 21') that are connected fixedly with the substrate (100), which are connected with one another via a bridge (25'), and a V-shaped flexural spring (30, 31; 32, 33) of the flexural spring device (30, 31; 32, 33) is attached to each of the opposite sides of the bridge (25') in such a way that the apex is situated on the bridge (25') and the limbs are spread towards the flywheel (10) with an opening angle.

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2. The micromechanical yaw rate sensor according to Claim 1,
wherein the opening angle is equal for the two V-shaped flexural springs (30, 31; 32, 33) of the flexural spring device (30, 31; 32, 33).

3. The micromechanical yaw rate sensor according to Claim 2,
wherein the V-shaped flexural springs (30, 31; 32, 33) of the flexural spring device (30, 31; 32, 33) are attached to the bridge in such a way that they form an X shape.

4. The micromechanical yaw rate sensor according to Claim 3,
wherein the opening angle is selected such that the natural frequency about the axis of rotation (z) situated perpendicular to the substrate surface is smaller than each natural frequency about an axis of rotation (x, y) situated parallel to the substrate surface.

5. The micromechanical yaw rate sensor according to one of the preceding claims,
wherein the bases (20; 21') at the opposite sides are fashioned in the shape of a wedge, and the bridge (25') connects the two wedge tips with one another.

6. The micromechanical yaw rate sensor according to one of the preceding claims, wherein the bridge (25') is suspended freely over the substrate (100) from the bases (21; 21').

7. The micromechanical yaw rate sensor according to one of the preceding claims, wherein it can be manufactured using silicon surface micromechanical technology or using another micromechanical technology.

Add A1?